

Low-pressure plasma system V55-G

Standard system for cleaning, activation, etching or coating



The system is standardly equipped with a swing door. A pull door is available as an option.

The unit is integrated in a 19" rack, which is equipped with rollers and height-adjustable feet.

The system can be used for the surface treatment methods cleaning, activation, etching and coating.

System features

- USB port
- Ethernet interface
- Remote maintenance (VPN)
- Microwave coupling from the top
- Swing door

Options

- Vacuum pump
- Ozone trap
- Up to two additional gas inlets
- Additional excitation frequencies (40 kHz, 13.56 MHz)
- Rotary drum for the treatment of bulk material
- Rotary table
- Pullout door
- Automatic door opening
- Soft start and slow vent

Technical data

Dimensions of the system (W x D x H): 670 x 900 x 1,850 mm

Dimensions of the chamber (W x D x H): 400 x 460 x 340 mm

Plasma excitation frequency: Microwave (2.45 GHz)

Microwave power: 100-1,200 W

Gas inlets with mass-flow-control: 2 channels

Power supply: 230/400 V, 50/60 Hz

Power input: 2,2 kVA

Vacuum gauge: Baratron



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The variable standard system V55-G has a high process operating flexibility because of its two gas channels and three optional plasma generating frequencies.